

Presenter	Institute	Topic	Notes
Chinorat Kobdaj	SUT	Detector Geometry	<ul style="list-style-type: none"> - Model of Inner Barrel completed - Model of Inner Service Barrel : ongoing - Model of the services, in particular the power distribution module (DC-DC converters) should have priority. Target April '15
Magnus Mager	CERN	Pixel Chip characterization	<ul style="list-style-type: none"> - MISTRAL FSBB-M0 results - ALPIDE results <ul style="list-style-type: none"> • CERN test beam • Pohang test beam (Pusan) - Validation of both architectures completed - Work on explorer (Pusan) - SEL tests
KyungEon Choi	Pusan	Pixel Chip characterization	<ul style="list-style-type: none"> - Si-Lab ready. Clean-room is being set-up - Characterization of Expliorer-1 irradiated at 10^{13} n/cm² ongoing - Test at Pohang (60MeV e) of irradiated Explorer-1 chip and pALPIDE-1 - Schedule for Pohang facility in 2015: first slot of one week in March/April? TBC
Jong-han Park	Inha	Pixel Chip characterization	<ul style="list-style-type: none"> - Lab test of (6 thin + 1 thick) pALPIDE-1 chips using the chip internal pulsing system (S-curve, noise, thresholds) pulse system and radioactive source (⁵⁵Fe) (Hit maps). Measurements done at Vbb=0V. - Participation in the Pohang test campaign - It is proposed to look at individual faulty pixels (if any) and identify the probability that the fault is related to the collection diode => does the circuit respond correctly to the pulsing system?
Kritsada Kittimanapun	SLRI	Pixel Chip characterization	<ul style="list-style-type: none"> - Availability of 1 Gev e beam for about 20h/d - 1 Gev e beam is suitable for the characterization of ITS sensors - current intensity too high (~mA) - Short term set-up: tests with very thick lead absorber (5 – 60 mm) + lead collimator. Emerging beam non

			<p>monochromatic + very large background from secondary particles.</p> <p>- Planned set-up (temporarily): use 4-degree magnet as energy selector (BTF at DAFNE). This set-up will be ready by June 2015.</p> <p>- Long-term plan (2 years) to develop a set-up to provide low-intensity monochromatic beams.</p>
Jirawat Prabket	TMEC	Post-processing	<p>- QA of Si raw wafers</p> <ul style="list-style-type: none"> • 4 point resistivity measurements • SEM cross section pictures • SRP measurements <p>Issue: identified large discrepancy between values quoted by wafer supplier and measured values. (Discussion with Petra)</p> <p>- Si micro-channels</p> <p>- Coordination of STARS activities on thinning & (laser) dicing</p>
Petra Riedler	CERN	Post-processing	<p>Wafer procurement and QA</p> <ul style="list-style-type: none"> - surface resistivity - SRP measurement - XSEM inspection <p>Plating (IZM, TMEC, Pacthec)</p> <ul style="list-style-type: none"> - Passivation of all areas outside contact pads - Ni deposition (3-5 um) - Au deposition (~50-100nm) <p>Thinning & Dicing</p> <ul style="list-style-type: none"> - Diamond wheel pre-dicing before grinding - DBG (Rockwood) - Laser dicing after grinding (STARS) <p>Visual Inspection QA</p> <ul style="list-style-type: none"> - Reference to Esa presentation <p>Laser soldering</p> <ul style="list-style-type: none"> - General optimization (refinement) of the procedure - Intensive work to classify soldering contacts using and cross-correlating various methods: integrated power, temperature, electrical test, metallurgical cross-section X-ray image <p>Transport Test</p>
Youngil Kwon	Yonsei	Chip series test	<p>- Test system. Two companies contacted. Cost of the test system:</p> <ul style="list-style-type: none"> - EC3 (small company): 140 kCHF

			<ul style="list-style-type: none"> - GENESEM (large company): 200 kCHF; - position accuracy (25um x 25um); - Probe card needles: maximum overdrive vs. potential damage to the pads is being evaluated; - Test procedure: is the optical (laser) test needed? - Specifications for test system, including test procedure, should be prepared by Feb 2015 (Yonsey+CERN).
Esa Prakasa	LIPI	QA	<ul style="list-style-type: none"> - QA for single pixel chip test <ul style="list-style-type: none"> - Thickness of pads => is it needed; - interconnection (daisy chain) lines, => not needed in CMOS chip - presence of cracks on the pads - missing in presentation: chip dimensions and inspection of quality of the edges; - QA for modules assembly: same tests as for single chip + position of chip wrt external markers (available within field of view centered around the chip markers) - QA for FPC: not yet started - Define specifications for visual inspection by Feb 2015
Vito Manzari	INFN	Outer barrel	<ul style="list-style-type: none"> - Procedure for module assembly - Chips are inspected visually before mounting them on the FPC. Can this replace the visual inspection carried out at chip series test? - Test System: VME interface only for distribution of power supplies. Should we consider in the next version a standalone power block.
Antonello Di Mauro	INFN	Laser Soldering, Automatic assembly Machine	<ul style="list-style-type: none"> - Laser soldering - Module assembly system <ul style="list-style-type: none"> • Scope of the tendering • Specifications • Baseline + options
Bon-Hwi	Pusan	Module Construction	<ul style="list-style-type: none"> - Setting-up lab for module assembly - Transport test: 6 out of 17 chips damaged - Laser soldering QA <ul style="list-style-type: none"> - Categorize soldering type - Check the measured values - Data analysis
Xiangming Sun	CCNU	Module Assembly at	<ul style="list-style-type: none"> - Automation of chip placement: automatize the correction of chip final

		CCNU	position. - Comment: automation of any other operation is not justified
Arshad Bhatti	COMSATS	Pixel chip simulations	- TCAD simulations: simulations performed for ideal doping profiles (constant average doping with Gaussian spread).
Jibran	COMSATS	Readout Electronics	Test system for IB data transmission: board should be constructed ASAP. One PhD student from CERN will work in close collaboration with COMSATS.
Dong Wang	CCNU	High-speed link evaluation	- Evaluation of GBT link (ongoing) using Xilinx KC705 (ongoing) - High-speed data transport (Jesd204b) evaluated using an fast ADC form Analogue Devices and the KC705. => comment: Xilinx cannot be used for the implementation of the Readout Unid because sensitive to SEU.
Ann Silapunt	KMUTT	Electronics	- Introduction of the group and plans. - Master student to work on - Welcome!!!